## §16. ICRF Mode Conversion Heating Experiments

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At ICRF heating experiments, the applied frequency was selected at $\mathrm{f}=25.6 \mathrm{MHz}$, because the magnetic field strength was 1.5 T in the 2nd cycle. In this situation, the ion cyclotron resonance and the mode conversion layer were located on the inner high field side: at half radius and at 0.650.75 of normalized radius, respectively. RF power is transmitted to each. RF antenna by a high power RF generator via a liquid impedance matching system.

An ICRF heating was applied to the ECH-produced plasma at the power level of about 300 kW for 0.2 seconds as shown in Fig.1[1]. The target plasma consisted of a majority of He ions and a minority of H ions. A pulse length of hydrogen gas has been able to change the ratio of H ions as shown in the bottom column of Fig.1. ICRF heating is started 0.15 seconds after ECH is started The increase (in solid line) in the stored plasma energy was observed to be the same as with ECH only (dashed line) as shown in the top column. The maximal stored plasma energy was observed at the end of ECH power, which is at 0.42 seconds. ICRF heating shows the same performance as ECH. The ECH target plasma has an average electron line density, $\mathrm{n}_{\mathrm{e}}=8.5 \times 10^{18} \mathrm{~m}^{-3}$ with a central electron temperature, $\mathrm{T}_{\mathrm{e} 0}=400 \mathrm{eV}$. The increase in the stored plasma energy is proportional to the applied ICRF power up to 300 kW . The stored plasma energy with ECH only is 13 kJ . The maximal increase is found to be 13 kJ at $\mathrm{P}_{\mathrm{ICRF}}=300 \mathrm{~kW}$, which has been obtained at a little longer overlay of ECH and ICRF heating than that in Fig.1.

A series of experiments about the results of changing the ratio of number of injected atomic hydrogen (H) to that of atomic helium (He) was carried out as shown in Fig.2. The number of H was changed by changing a pulse length of a hydrogen gas puffing at the constant flow rate of 0.82 $\mathrm{Pam}^{3} / \mathrm{sec}$ as shown in the bottom column of Fig.1. The numbers of He were constant at $0.194 \mathrm{Pam}^{3}$ as shown in the midde column of Fig.1. The abscissa of Fig. 2 is the minority ratio of H to $\mathrm{He}, \mathrm{H} /(\mathrm{He}+\mathrm{H})$. The increase in the plasma stored energy $\mathrm{dW}_{\mathrm{p}}$ with the application of ICRF heating is plotted with solid circles in Fig.2. The maximal $d W_{p}$ is observed at $\mathrm{H} /(\mathrm{He}+\mathrm{H})=30 \%$.

The increase in the stored energy of electrons, $\mathrm{dW}_{\mathrm{e}}$ can be calculated by integrating a product of the electron density and the electron temperature measured by a 13 channel-HCN laser and 130-spatial-point Thomson scattering. Open circles indicate the increase in $\mathrm{dW}_{\mathrm{e}}$, which is also plotted in Fig. 2. A subtraction of $\mathrm{dW}_{\mathrm{e}}$ from $\mathrm{dW}_{\mathrm{p}}$ shows an increase in the stored ion energy, $\mathrm{dW}_{\mathrm{i}}$, which is also plotted with open
squares in Fig.2. The stored electron energy is small at the lower minority ratio of $\mathrm{H} /(\mathrm{He}+\mathrm{H})$ and increases with the proportion of the minority hydrogen ratio. The maximal electron stored energy is observed at $\mathrm{H} /(\mathrm{He}+\mathrm{H})=25 \%$.

## Reference

[1] R.Kumazawa et al., in the proceeding of $13^{\text {th }}$ Topical Conference on Applications of Radio Frequency Power to Plasmas (1999).


Fig. 1 Time evolution of plasma parameters; at top column, ICRF heating power, ECH power, and plasma stored energy, at middle column, average electron density and He gas puffing and at bottom column, ECE signal and $\mathrm{H}_{2}$ gas puffing with and without ICRF heating.


Fig. 2 Dependence of increase in stored energies of $d W_{p}, \mathrm{dW}_{\mathrm{e}}$ and $\mathrm{dW}_{\mathrm{i}}$ on the gas puffing rate of $\mathrm{H} / \mathrm{H}+\mathrm{He}$.

